

Electronic Patent Application Fee Transmittal

Application Number:	10518371			
Filing Date:	28-Dec-2004			
Title of Invention:	Plasma chemical vapor deposition method and plasma chemical vapor deposition device			
First Named Inventor/Applicant Name:	Hiroshi Mashima			
Filer:	Marvin Jay Spivak/Isiah Avila			
Attorney Docket Number:	263787US2PCT			

Filed as Large Entity

U.S. National Stage under 35 USC 371 Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
-------------	----------	----------	--------	----------------------

Basic Filing:

Pages:

Claims:

Miscellaneous-Filing:

Petition:

Patent-Appeals-and-Interference:

Post-Allowance-and-Post-Issuance:

Extension-of-Time:

Extension - 2 months with \$0 paid	1252	1	490	490
------------------------------------	------	---	-----	-----

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Request for continued examination	1801	1	810	810
Total in USD (\$)			1300	